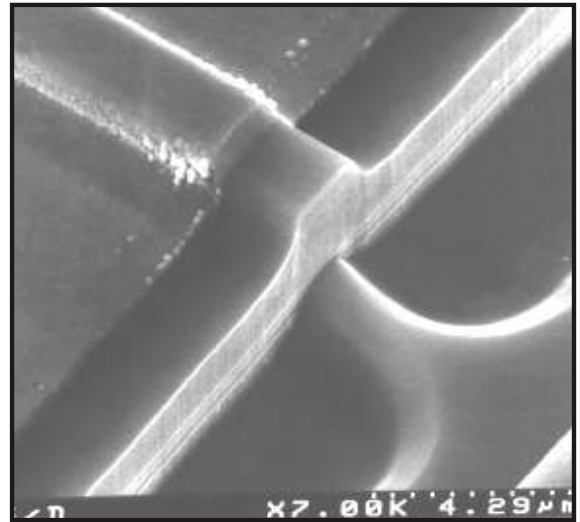
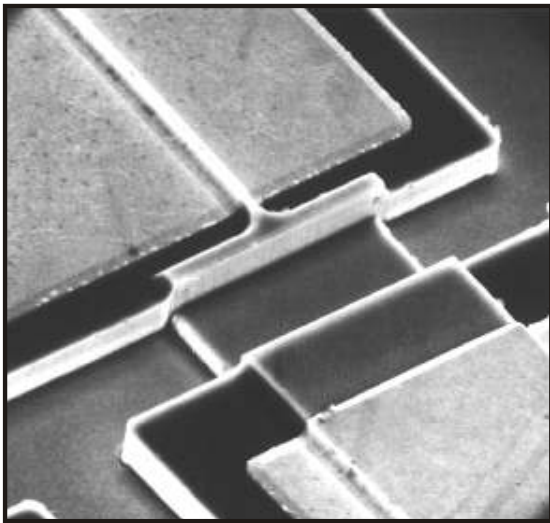


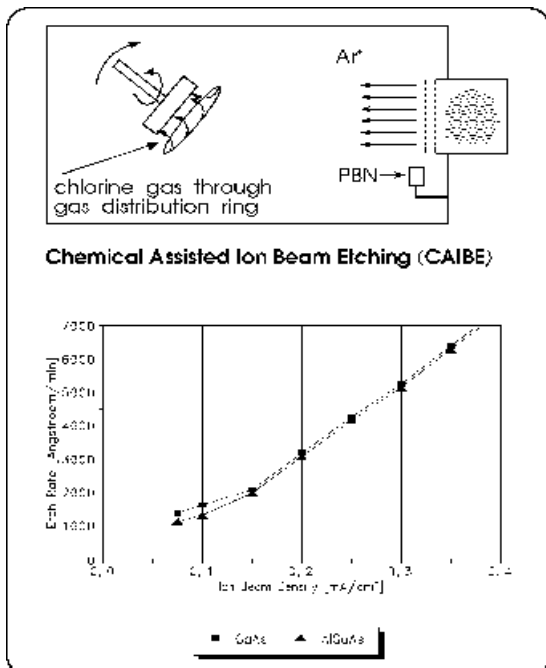
# Ionfab Data

## Laser Mirrors: GaAs / GaAlAs - CAIBE



6 µm deep, anisotropic GaAs / GaAlAs - CAIBE for MQW Ridge Waveguide Laser (by the courtesy of IBM Zurich)

### Ionfab 300 Plus



**Technology:**

- Chemical Assisted Ion Beam Etch
- Cl<sub>2</sub> / Ar - process
- Rotating substrate with adjustable tilt
- Ion source: RF
- PBN Beam Neutralisation, filamentless
- Ion Optics / Grid Set :
- Low Energy / low Microdivergence
- Effective substrate cooling

**Results:**

- Highly anisotropic etch with 'mirror quality'
- Mask: Photoresist or SiO<sub>2</sub>